



PATENT

Atty. Dkt. No. AMAT/6493/ETCH/SILICON/JB1

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:  
Nallan, et al.

Serial No.: 09/993,240

Confirmation No.: 6869

Filed: November 13, 2001

For: Apparatus for Controlling a Thermal Conductivity Profile for a Pedestal in a Semiconductor Wafer Processing Chamber

MAIL STOP RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**Group Art Unit:** 1763

**Examiner:** Ram N. Kackar

CERTIFICATE UNDER 37 CFR 1.8

I hereby certify that this correspondence and the documents referred to as attached therein are being deposited on March 18, 2004 with the United States Postal Service in an envelope as "Express Mail Post Office to Addressee," mailing label No. EV335477743US addressed to: Mail Stop RCE, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450

March 18, 2004 Gei Hamond  
Date Signature

Date

## **PRELIMINARY AMENDMENT**

Applicants, in accordance with 37 C.F.R. §1.114(c), request consideration of the following amendments prior to the examination of the attached Request for Continued Prosecution of the above identified application.

The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/6493/AOP, for any fees, including extension of time fees or excess claim fees, required to make this amendment timely and acceptable to the Office.

Amendments to the claims are reflected in the listing of claims which begins on page 2 of this paper. Remarks begin on page 8 of this paper.